Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L17	13	(US-20050023596-\$ or US-20040119064-\$ or US-20050009276-\$).did. or (US-6153494-\$ or US-5851881-\$ or US-6461915-\$ or US-6271143-\$ or US-5943585-\$ or US-5278438-\$ or US-6882025-\$ or US-5854114-\$ or US-6753569-\$ or US-5387534-\$).did.	US-PGPUB; USPAT	OR	ON	2006/03/21 11:32
L18	10879	semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric) and (trench or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (pattern\$3 or remov\$3)	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:40
L19	9960	18 and ((liner or insulat\$3 or dielectric or \$2oxid\$4) with (trench or opening or slot or groove or via))	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:41
L20	4415	19 and (self-align\$3 or (self near2 align\$3))	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:43
L21	4211	20 and (gate with (dielectric or insulat\$3 or \$2oxid\$4))	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:48
L22	3599	21 and ((spacer or sidewall or (side adj wall)) with (remov\$4 or etch\$3 or pattern\$3))	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:50
L23	3242	22 and (@ad<"20030731" or @rlad<"20030731")	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR .	ON	2006/03/21 14:00
L24	3154	23 and (mask\$4 or resist\$3 or maskresist\$3 or photomask or photoresist)	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:42
L25	235	24 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric) and (trench or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (pattern\$3 or remov\$3)).clm.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:48
L26	216	25 and ((liner or insulat\$3 or dielectric or \$20xid\$4) with (trench or opening or slot or groove or via)).clm.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:44
L27	173	26 and (((spacer or sidewall or (side adj wall)) with (remov\$4 or etch\$3 or pattern\$3)) and ((spacer or sidewall or (side adj wall)) with (remov\$4 or etch\$3 or pattern\$3))).clm.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:42
L28	93	27 and (self-align\$3 or (self near2 align\$3)).clm.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:52
L29	86	28 and (fill\$4)	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:44

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84	28 and ((liner or insulat\$3 or dielectric or \$20xid\$4) with (trench or opening or slot or groove or via) with fill\$3)	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:51
213	(semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (pattern\$3 or remov\$3) and (gate with (dielectric or insulat\$3 or \$20xid\$4))). clm.	US-PGPUB	OR	ON	2006/03/21 14:11
162	31 and (((spacer or sidewall or (side adj wall)) with (remov\$4 or etch\$3 or pattern\$3))).clm.	US-PGPUB	OR	ON	2006/03/21 11:50
90	32 and ((liner or insulat\$3 or dielectric or \$20xid\$4) with (trench or opening or slot or groove or via) with fill\$3).clm.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:51
37	33 and (self-align\$3 or (self near2 align\$3)).clm.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 11:52
2521	438/261,400,700.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 13:03
43	35 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (pattern\$3 or remov\$3) and (gate with (dielectric or insulat\$3 or \$20xid\$4)))	US-PGPUB	OR	ON	2006/03/21 14:07
42	36 not (17 34)	US-PGPUB	OR	ON	2006/03/21 13:55
34	37 and (@ad<"20030731" or @rlad<"20030731")	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 14:07
98	438/400.ixr.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 14:11
3	39 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (pattern\$3 or remov\$3) and (gate with (dielectric or insulat\$3 or \$20xid\$4)))	US-PGPUB	OR	ON	2006/03/21 14:10
3	39 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4)	US-PGPUB	OR	ON	2006/03/21 14:10
711	438/400.cxr.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 14:14
3	42 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (pattern\$3 or remov\$3))	US-PGPUB	OR	ON	2006/03/21 14:12
9	42 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)))	US-PGPUB	OR	ON	2006/03/21 14:12
	213 162 90 37 2521 43 42 34 98 3 711	or opening or slot or groove or via) with fill\$3) 213 (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (pattern\$3 or remov\$3) and (gate with (dielectric or insulat\$3 or \$20xid\$4))). clm. 162 31 and (((spacer or sidewall or (side adj wall)) with (remov\$4 or etch\$3 or pattern\$3))).clm. 90 32 and ((liner or insulat\$3 or dielectric or \$20xid\$4) with (trench or opening or slot or groove or via) with fill\$3).clm. 37 33 and (self-align\$3 or (self near2 align\$3)).clm. 43 35 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (pattern\$3 or remov\$3) and (gate with (dielectric or insulat\$3 or \$20xid\$4))) 36 not (17 34) 37 and (@ad<"20030731" or @rlad<"20030731") 438/400.ixr. 3 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or insulat\$3 or \$20xid\$4)) 3 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or insulat\$3 or \$20xid\$4)) 3 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or insulat\$3 or \$20xid\$4)) 3 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4) 42 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4) 42 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate	or opening or slot or groove or via) with fill\$3) 213 (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (pattern\$3 or remov\$3) and (gate with (dielectric or insulat\$3 or \$20xid\$4))). clm. 162 31 and (((spacer or sidewall or (side adj wall)) with (remov\$4 or etch\$3 or pattern\$3))).clm. 90 32 and ((liner or insulat\$3 or dielectric or \$20xid\$4) with (trench or opening or slot or groove or via) with fill\$3).clm. 37 33 and (self-align\$3 or (self near2 align\$3)).clm. 2521 438/261,400,700.ccls. 2521 438/261,400,700.ccls. 2521 438/261,400,700.ccls. 35 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (pattern\$3 or remov\$3) and (gate with (dielectric or insulat\$3 or \$20xid\$4))) 42 36 not (17 34) 33 and (@ad<"20030731" or @rlad<"20030731") 34 438/400.ixr. 35 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or insulat\$3 or \$20xid\$4)) 42 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or insulat\$3 or \$20xid\$4)) 35 and (gate with (dielectric or insulat\$3 or \$20xid\$4)) 36 not (17 34) 37 and (@ad<"20030731" or @rlad<"20030731") 39 and (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or insulat\$3 or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (pattern\$3 or remov\$3)) and (gate with (dielectric or \$20xid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (spacer or sidewall or (side adj wall)) and planariz\$4 and (spacer or sidewall or (side adj wall)) and planariz\$4 and	comparing or slot or groove or via) with fill\$3 USPAT; USOCR; EPC; JPO; IBM_TDB US-PGPUB US	or opening or slot or groove or via) with fill\$3) (semiconductor and (substrate or wafer or board) and conduct\$4 and (insulat\$4 or dielectric or \$2xxid\$4) and (trench or via or opening or slot or groove) and gate and (spacer or sidewall or (side adj wall)) and planariz\$4 and (pattern\$3 or remov\$3) and (gate with (dielectric or insulat\$3 or \$2xxid\$4)). clm. 162 31 and (((spacer or sidewall or (side adj wall)) with (remov\$4 or etch\$3 or pattern\$3)).clm. 163 32 and ((liner or insulat\$3 or dielectric or \$2xxid\$4) with (trench or opening or slot or groove or via) with fill\$3).clm. 164 33 and (self-align\$3 or (self near2 align\$3)).clm. 165 37 38 and (self-align\$3 or (self near2 align\$3)).clm. 166 38 and (self-align\$3 or (self near2 align\$3)).clm. 177 38 and (self-align\$3 or (self near2 align\$3)).clm. 178 39 and (self-align\$3 or (self near2 align\$3)).clm. 179 30 and (self-align\$3 or (self near2 align\$3)).clm. 170 30 and (self-align\$3 or (self near2 align\$3)).clm. 171 30 and (self-align\$3 or (self near2 align\$3)).clm. 172 31 and (self-align\$3 or (self near2 align\$3)).clm. 173 32 and (self-align\$3 or (self near2 align\$3)).clm. 174 35 and (self-align\$3 or (self near2 align\$3)).clm. 175 36 and (self-align\$3 or (self-align\$3 or (self-align\$3)).clm. 175 37 38 and (self-align\$3 or (self-align\$3 or (self-align\$3)).clm. 177 38 39 and (self-align\$3 or (self-align

L45	876	438/400.ccls.	US-PGPUB;	OR	ON	2006/03/21 14:35
			USPAT; USOCR; EPO; JPO; IBM_TDB			
L46	0	H01L21/311.FIPC.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 14:31
L47	0	21/311.FIPC.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 14:23
L48	0	21/311.FIPC.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/03/21 14:23
L50	24	H01L21/311.IPC.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 14:32
L51	1094	438/700.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 14:36
L52	1990	257/E21.582.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2006/03/21 15:33
L53	570	257/E21.295.ccls.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR _	ON	2006/03/21 15:33
S1	1	"20050023596"	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/04/28 19:44
S2	139	Hsieh-Chia-ta.in.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/04/28 19:44
S3	1	S1 and (trench or strip\$3)	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/04/28 19:44
S4	101	S2 and (trench or strip\$3)	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/04/28 19:44
S5	10	S4 and liner	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/04/28 19:45

S6	1	"20050023596"	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/04/29 10:26
\$7	139	Hsieh-Chia-ta.in.	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/04/29 10:26
S8	1	S6 and (trench or strip\$3)	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/04/29 10:26
S9	101	S7 and (trench or strip\$3)	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/04/29 10:26
S10	10	S9 and liner	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/04/29 10:26
S11	9	("5231299" "5447884" "5597751" "5652161" "5851881" "6017795" "6074927" "6093611" "6110800").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/04/29 10:47
S12	7	("5173436" "5293560" "5387534" "5480821" "5496753" "5515321" "5559048").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/04/29 10:56
S13	33	("5851881").URPN.	USPAT	OR	ON	2005/04/29 11:44
S14	14	("5427968" "5614747" "5652161" "5851881" "5858840" "5879992" "5918125" "5950087" "5981340" "5989960" "6005807" "6130132" "6133098" "6153494").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/04/29 11:51
S15	13	("6204126").URPN.	USPAT	OR	ON	2005/04/29 12:00
S16	6	("6358796").URPN.	USPAT	OR	ON	2005/04/29 12:05
S17	13	("6204126").URPN.	USPAT	OR	ON	2005/04/29 12:09
S18	1	"6753569"	USPAT	OR	ON	2005/04/29 12:10
S19	7	("4631803" "5231299" "5447884" "5597751" "5652161" "5851881" "6013551").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/04/29 12:13
S20	7	("4631803" "5231299" "5447884" "5597751" "5652161" "5851881" "6013551").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/04/29 12:13
S21	0	("6753569").URPN.	USPAT	OR	ON	2005/04/29 12:14
S22	8	(US-20020055205-\$ or US-20050023596-\$).did. or (US-5387534-\$ or US-5851881-\$ or US-6153494-\$ or US-6204126-\$ or US-6734055-\$ or US-6753569-\$).did.	US-PGPUB; USPAT	OR	ON	2005/08/16 16:29
S23	4	("4914050" "4975384" "5234856" "5278438").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/08/16 16:43
S24	7	("5173436" "5293560" "5387534" "5480821" "5496753" "5515321" "5559048").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/10/21 13:21
S25	37	("5851881").URPN.	USPAT	OR	ON	2005/10/21 13:23
S26	180	transistor and ((trench adj isolat\$3) with (oxide near3 liner))	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/10/21 13:29

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S27	147	transistor and ((trench adj isolat\$3) with (oxide near liner))	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/10/21 13:30
S28	98	S27 and gate and (spacer or sidewall or (side adj wall))	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/10/21 13:31
S29	42	S28 and (remov\$3 with (spacer or sidewall or (side adj wall)))	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/10/21 13:31
S30	39	S29 and ((chemical adj vapor\$3 adj2 process\$3) or "CMP")	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/10/21 13:32
S31	32	S30 and well	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/10/21 13:32
S32	. 13	S31 and float\$4 and polysilicon	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/10/21 13:42
S33	19	S31 not S32	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/10/21 13:57
S34	6	("4797718" "4912535" "5043787" "5053839" "5084418" "5218221").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/10/21 13:53
S35	43	("5278438").URPN.	USPAT	OR	ON	2005/10/21 13:54
S36	10	S29 not S31	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/10/21 13:58
S37	56	S28 not S29	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/10/21 13:58
S38	1.	10/723842 and gibb	US-PGPUB; USPAT; USOCR; EPO; JPO; IBM_TDB	OR	ON	2005/10/21 14:59